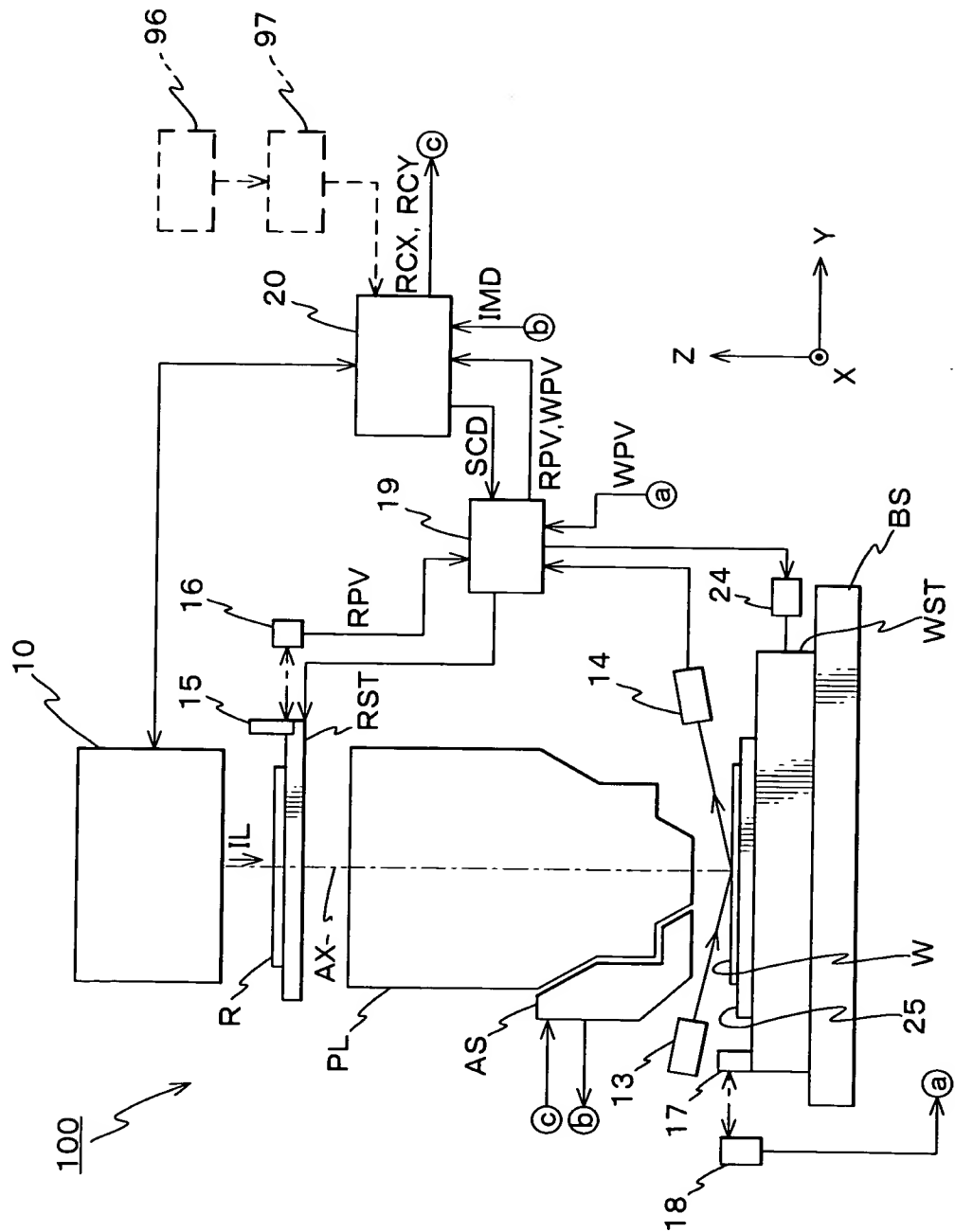


Fig. 1



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Fig. 2A

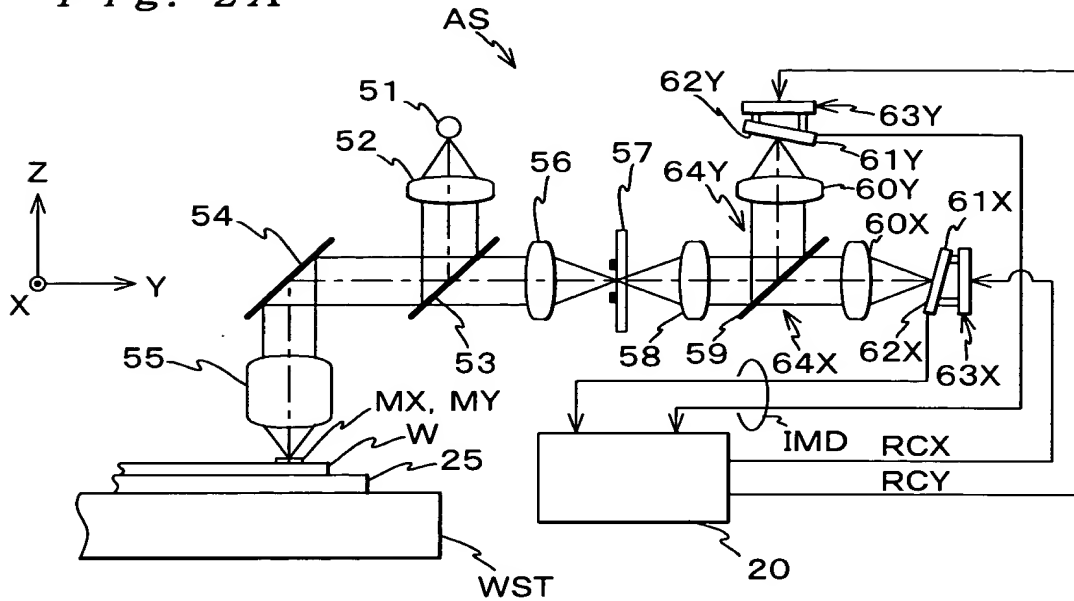


Fig. 2B

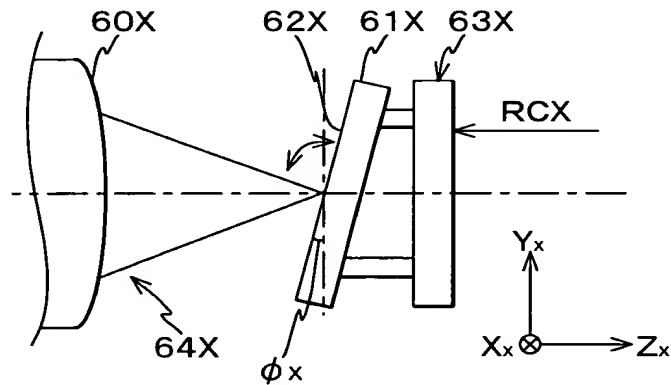
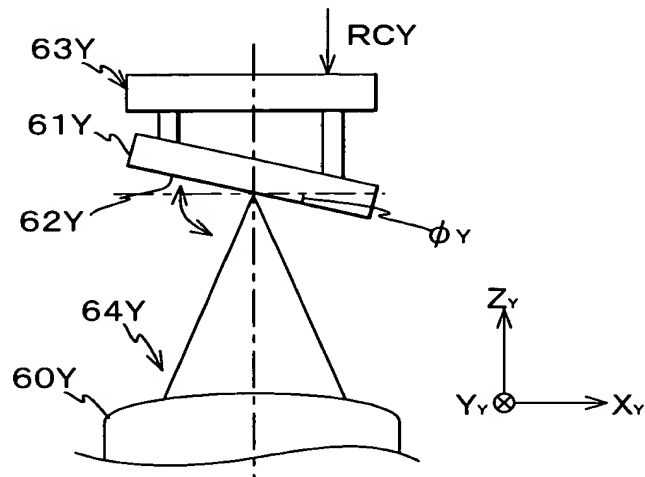


Fig. 2C



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Fig. 3A

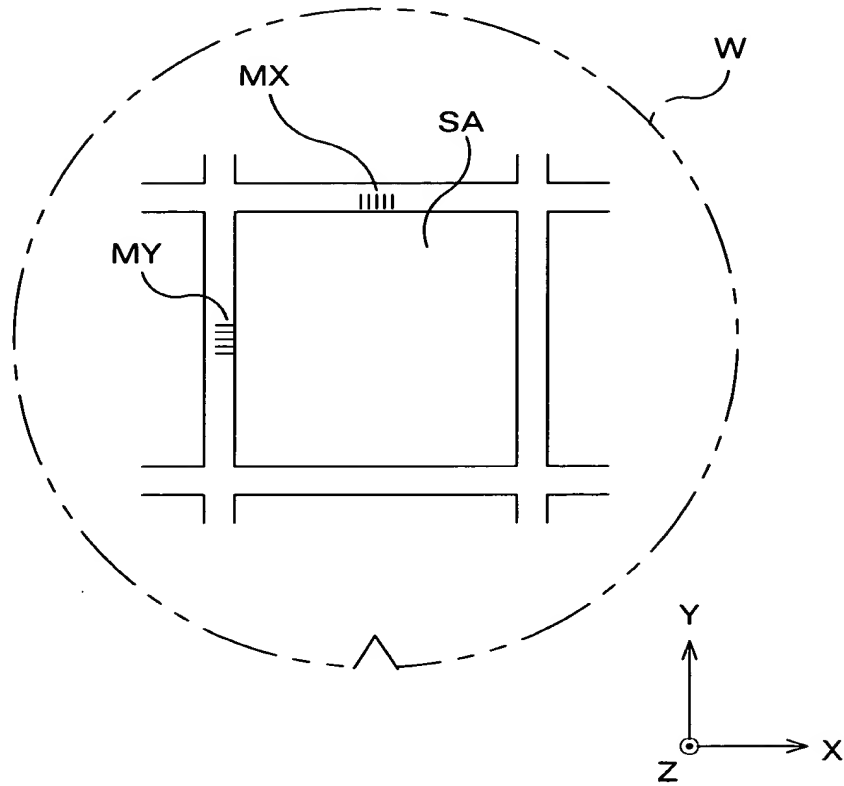
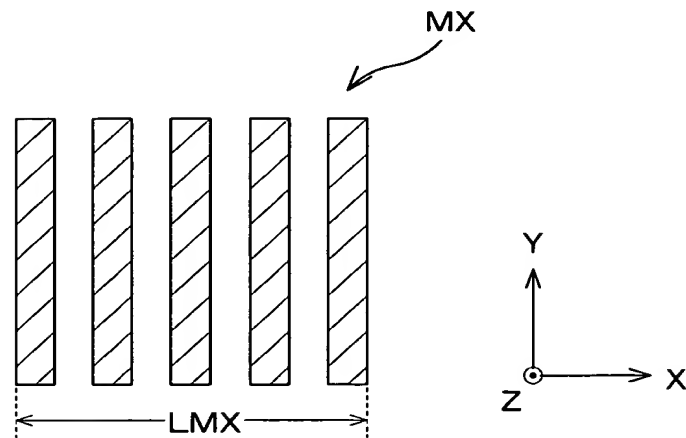


Fig. 3B



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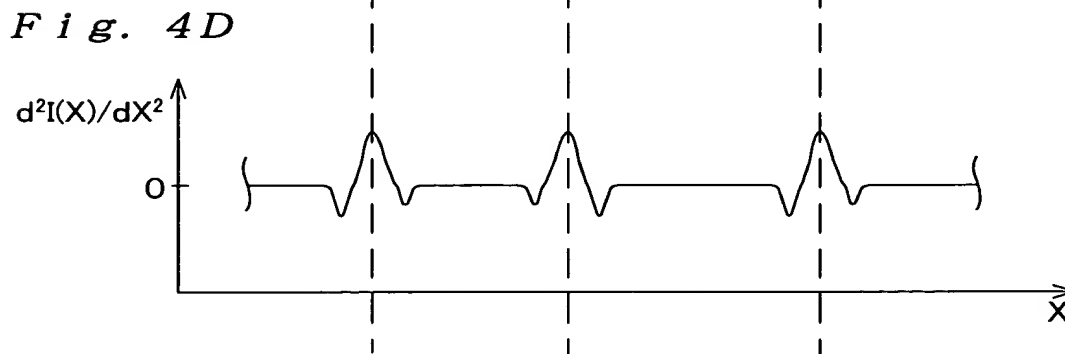
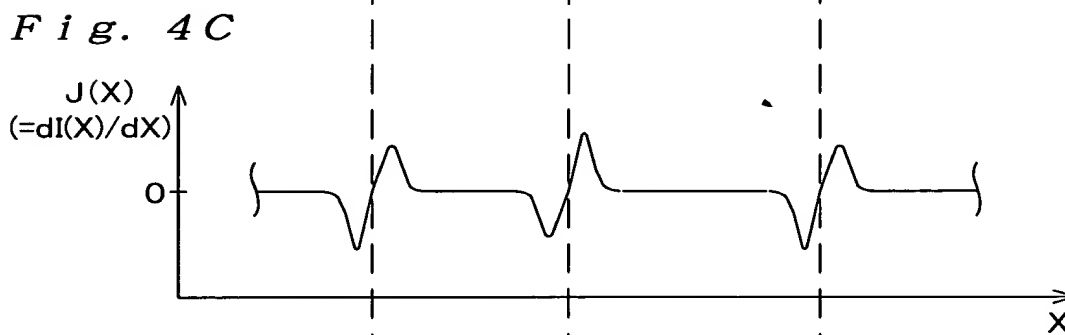
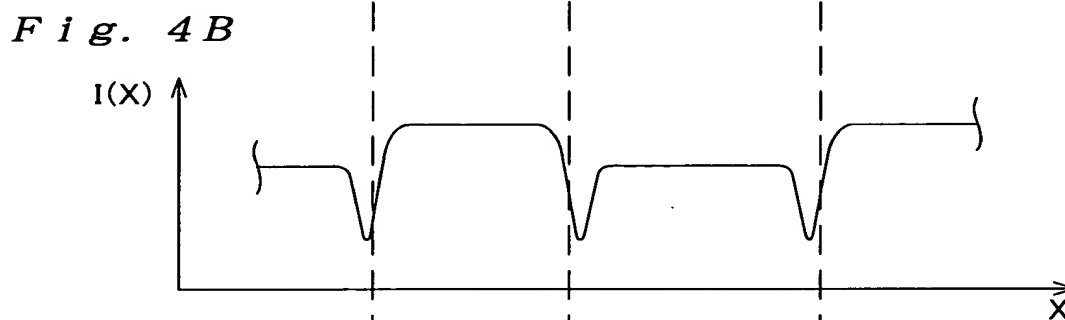
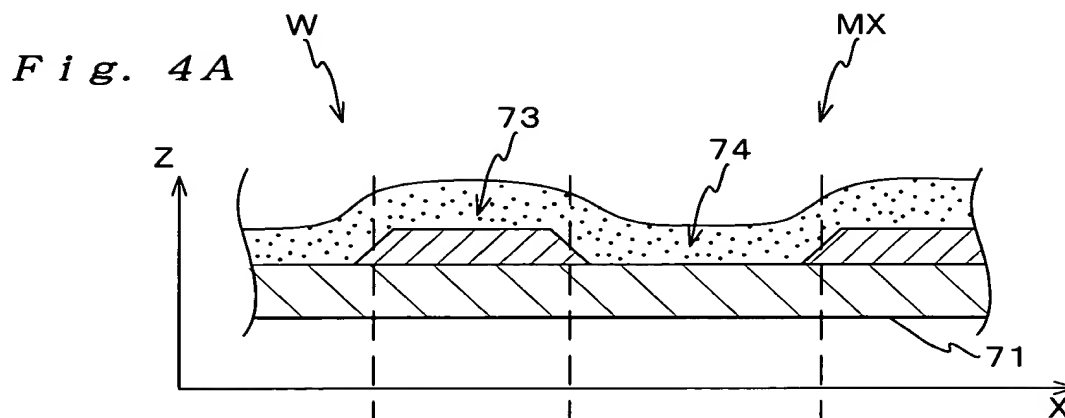


FIG. 4A

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Fig. 5A

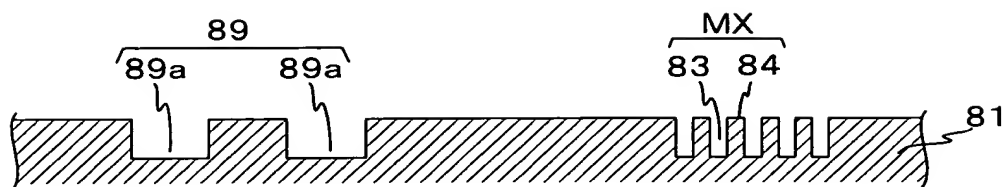


Fig. 5B

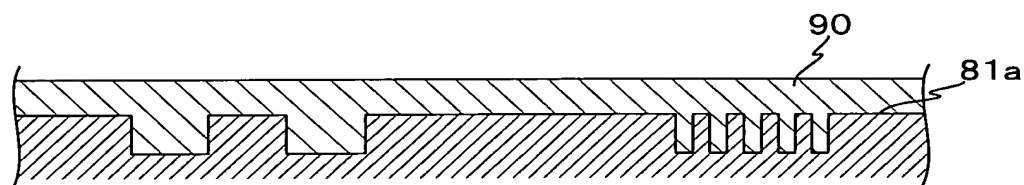


Fig. 5C

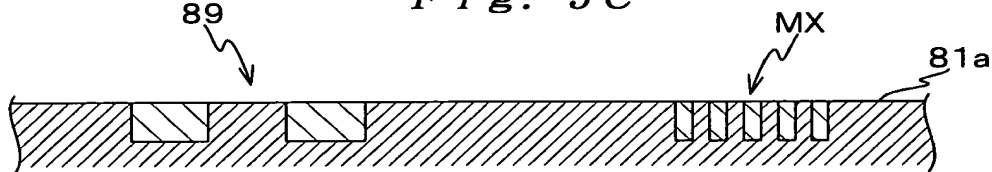


Fig. 5D

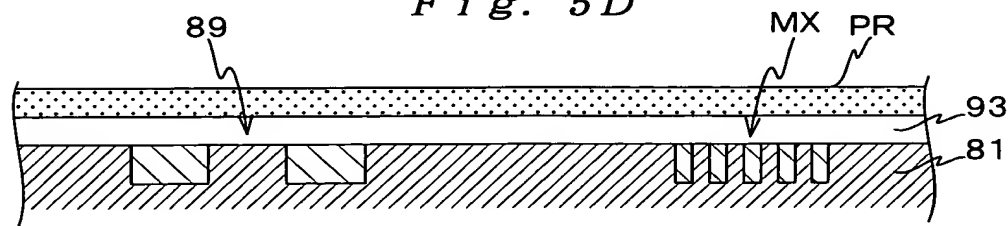
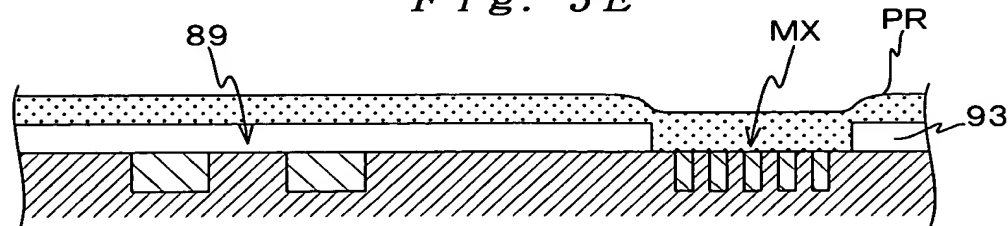


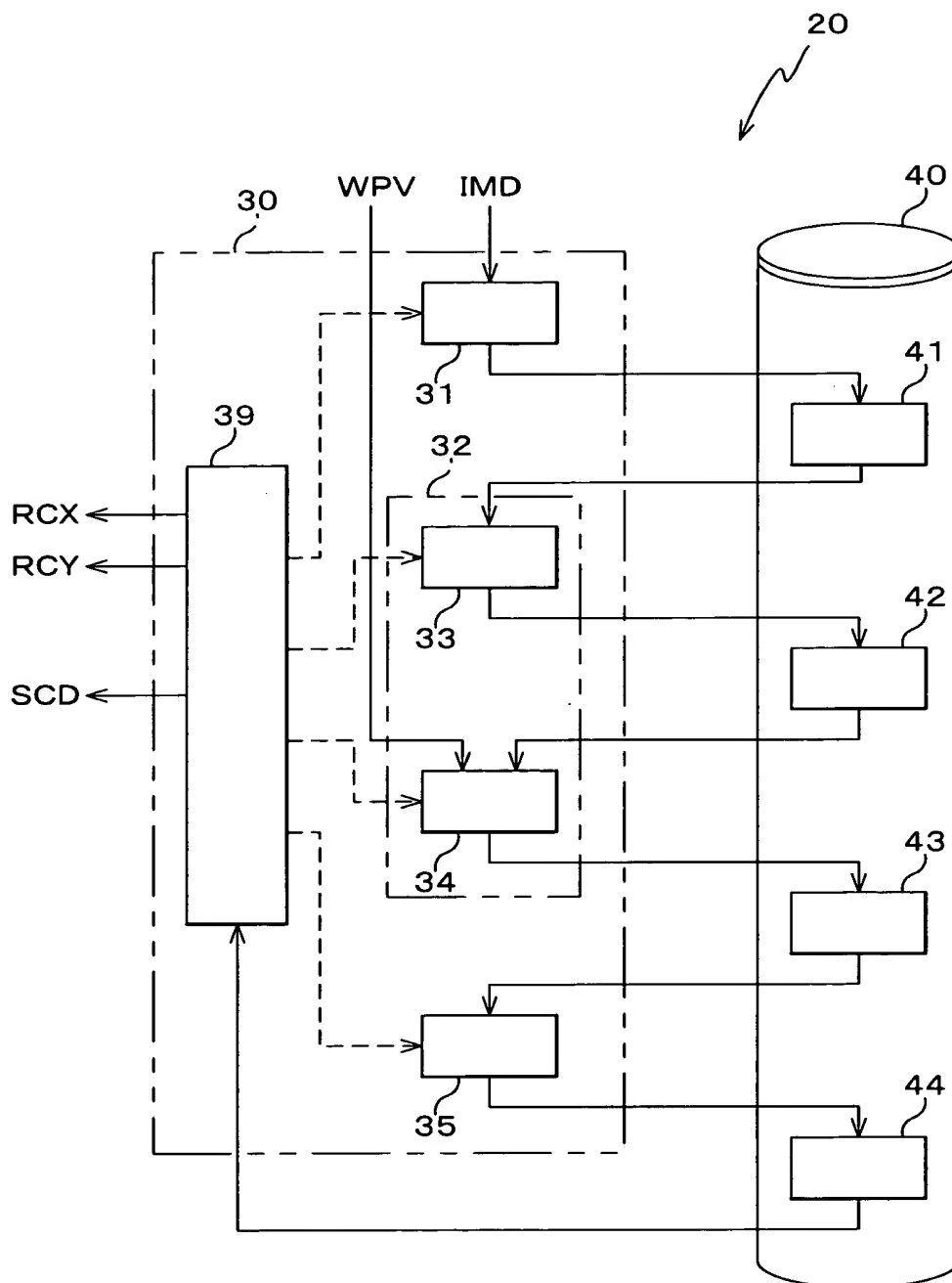
Fig. 5E



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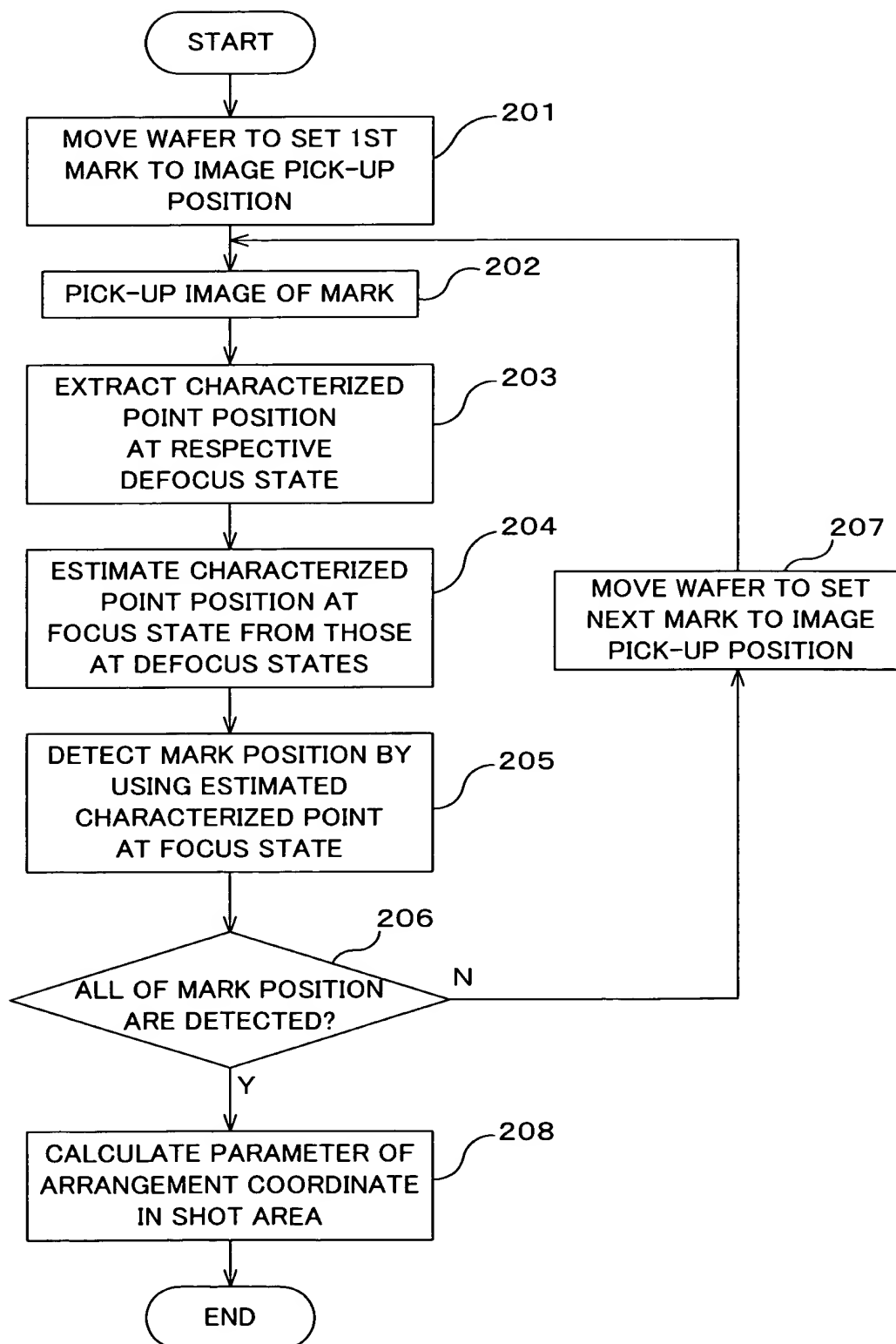
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Fig. 6



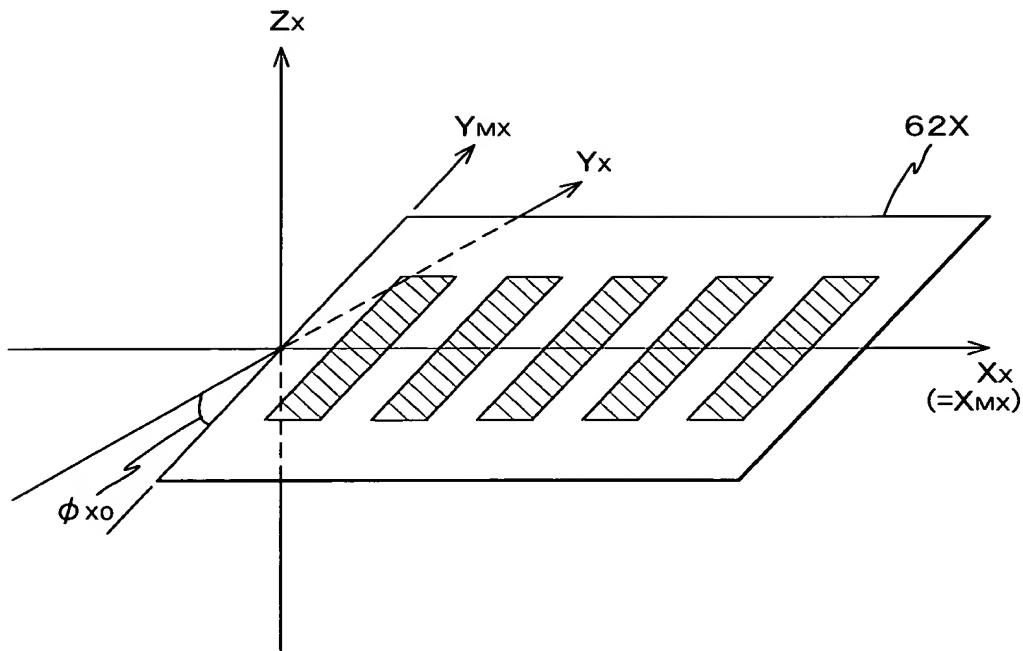
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Fig. 7



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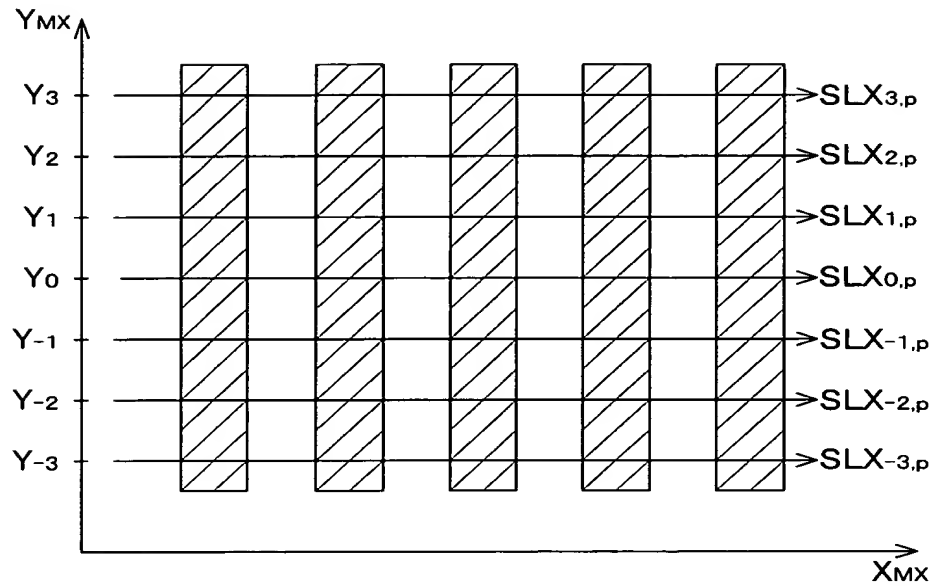
Fig. 8



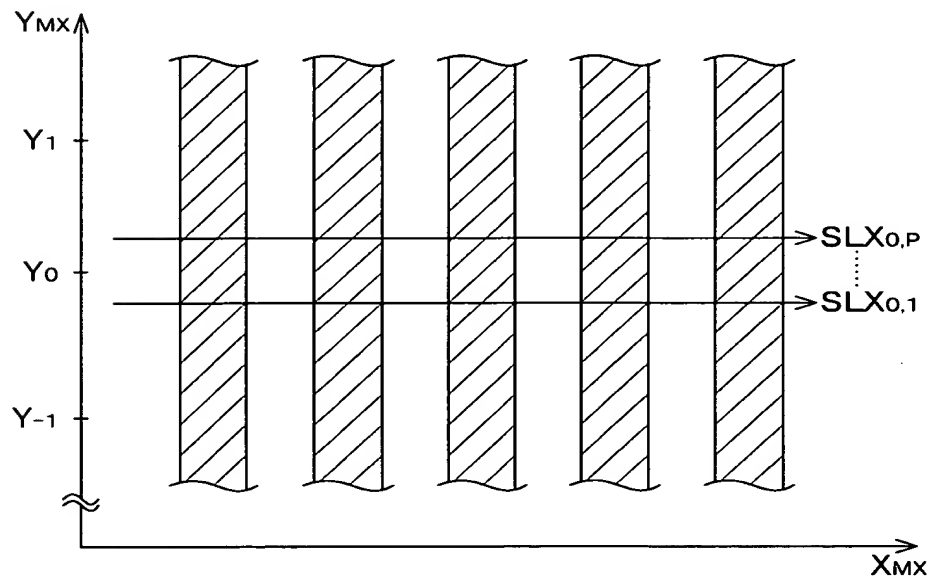
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F i g. 9 A



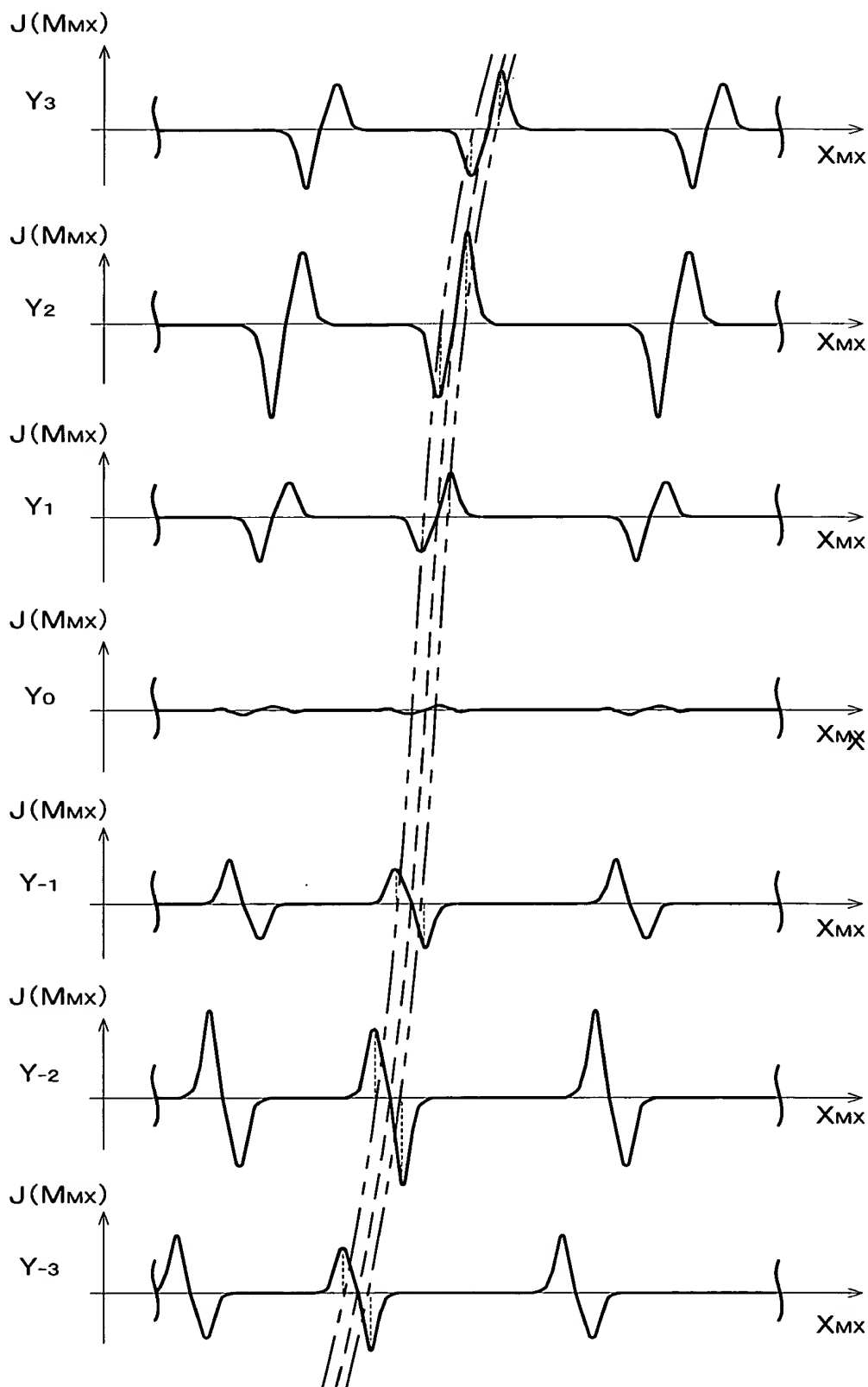
F i g. 9 B



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Fig. 10



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Fig. 11

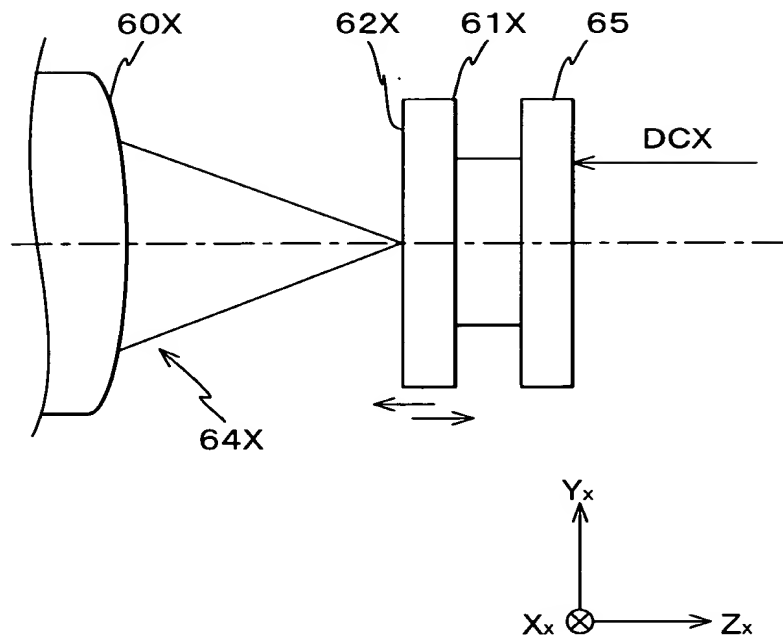


FIG. 11

```
graph TD; 301[DESIGN<br/>(FUNCTION, PERFORMANCE,<br/>PATTERN)] --> 302[MANUFACTURE MASK]; 302 --> 304[PROCESS WAFER]; 303[MANUFACTURE WAFER] --> 304; 304 --> 305[ASSEMBLE DEVICE]; 305 --> 306[INSPECT DEVICE]; 306 --> SHIPMENT["(SHIPMENT)"];
```

The flowchart illustrates a semiconductor manufacturing process. It begins with a box labeled 301 containing the text "DESIGN (FUNCTION, PERFORMANCE, PATTERN)". An arrow points down from box 301 to box 302, which contains "MANUFACTURE MASK". From box 302, an arrow points down to box 304, which contains "PROCESS WAFER". A second box, labeled 303 and containing "MANUFACTURE WAFER", has an arrow pointing down to box 304. From box 304, an arrow points down to box 305, which contains "ASSEMBLE DEVICE". From box 305, an arrow points down to box 306, which contains "INSPECT DEVICE". Finally, an arrow points down from box 306 to the text "(SHIPMENT)".

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Fig. 13

